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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

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of 2

Application Number 10/809,317 03/24/2004 Filing Date G. Ramanath First Named Inventor **Group Art Unit** 2813 Kielen, Erikt Colleen Roda **Examiner Name**

5002.02-1 Attorney Docket Number

U.S. PATENT DOCUMENTS					
Examiner Initials *	Cite No.	Document Number	Publication Date/	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevan Passages or Relevant Figures Appear
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	No.	Country Code ³ - Number ⁴ - Kind Code ⁵ (# known)			Passages or Relevant Figures Appear	T ⁰
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	OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS		
Examiner Initials *	Cite No.1	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T 2
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Examiner Signature	College Qof	Date Considered	12/1/05

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First Named Inventor	G. Ramanath	
Group Art Unit	2813	
Examiner Name	Kielen, Erikt Colleen Da	
Altomey Docket Number	5002.02-1	

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Collung (Raf) 05/02/06

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